

20/869

PATENT NUMBER AND
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10085753	FILING DATE 02/28/2002	CLASS 438/134	SUBCLASS 924.3	GAU 2862 1746	EXAMINER KORMANOV
----------------------	---------------------------	------------------	-------------------	---------------------	----------------------

**APPLICANTS: Tsuga Toshihito; Fube Minoru; Nakayama Kazutaka;

**CONTINUING DATA VERIFIED:

BEST AVAILABLE COPY

** FOREIGN APPLICATIONS VERIFIED:

JAPAN 2001-059776 03/05/2001

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no
35 USC 119 conditions met ☐ yes ☐ no

ATTORNEY DOCKET NO

Verified and Acknowledged Examiners's initials

TI-31620

TITLE : Method and device for removing particles on semiconductor wafers

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

ISSUE FEE		Assistant Examiner		Total Claims		Filing Date	
Amount Due	Date Paid						
		Primary Examiner		DRAWING			
				Sheets Drwg. Figs. Drwg. Print Fg.			
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE		Application Examiner			
<p>WARNING: The information disclosed herein may be restricted. Unauthorized disclosures may be prohibited by the United States Code Title 35, Sections 122, 181 and 368. Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.</p>							

FILED WITH:

☐ DISK (CRF)

☐ CD-ROM

(Attached in pocket on right inside file)